



520.34403CV4

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): T. MASUDA, et al  
Serial No.: 09/421,043  
Filed: October 20, 1999  
For: PLASMA ETCHING APPARATUS AND PLASMA ETCHING METHOD  
Group: 1763  
Examiner: A. Mulero

**AMENDMENT**

Mail Stop: Amendment (Fee)  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

November 2, 2006

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application in response to the Office Action dated May 2, 2006. The amendments are listed below.

Amendments to the Specification;

Amendment of the Claims; and

Remarks are included following the amendments.